Supporting Information

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Versatile grafting chemistry for creation of stable molecular layers on oxides

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Calculations of surface coverage of the molecular layers on SiO₂ and TiO₂ by XPS

The overall number of the atoms of interest (X) per unit area of TiO_2 , for example, can be calculated from the using:

$$N(X) = \frac{A(X)s(Ti)\rho(Ti, TiO_2)sin(\theta)exp(\frac{t}{\lambda(X, organic)sin(\theta)})}{A(Ti)s(X)exp(\frac{t}{\lambda(Ti, organic)sin(\theta)})}$$

where N(X) is number of atoms per unit area, A(X)/A(Ti) is the ratio of integrated XPS peak areas, s(Ti)/s(X) is sensitivity factor ratio between titanium and atom of interest, ρ (Ti, TiO₂) is number of Ti atoms per unit volume in SiO₂, λ (Ti, TiO₂) is inelastic mean free path (IMFP) of Ti photoelectrons in TiO₂, t is thickness of the layer, λ (X, organic) and λ (Ti, organic) are IMFPs of X and Ti in organic films, respectively.¹ The angle θ is the take-off angle of photoelectrons with respect to the sample plane ($\theta = 45^{\circ}$). Neglecting the surface roughness² and using similar approximation of IMFPs of organic self-assembled monolayers from previous studies [λ (A°) =

9.0 + 0.022*E(eV)] where E(eV) is the kinetic energy in electron volts, 3 $\lambda(X, organic) \sim 2.8-3.5$ nm and $\lambda(Ti, TiO_2) \sim \lambda(Ti 2p, organic) = 3.3$ nm. Since $\lambda(X)$, organic) $\sim \lambda(Ti 2s, organic)$ and t <

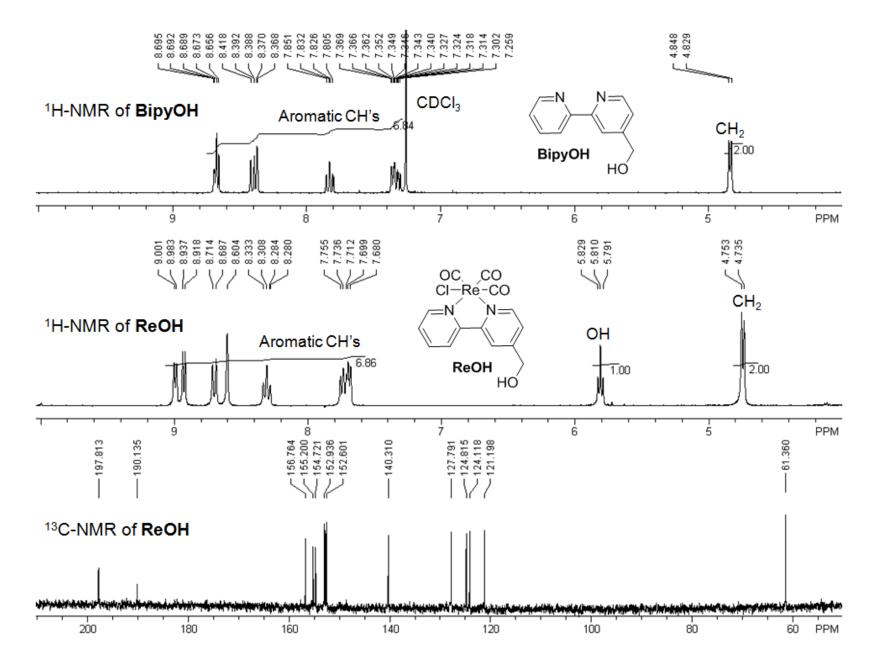
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$$\lambda \text{ for thin organic layer approximation, we conclude that } \frac{exp(\frac{t}{\lambda(X,organic)sin(\theta)})}{exp(\frac{t}{\lambda(Ti,organic)sin(\theta)})} \approx 1. \quad \text{Using}$$

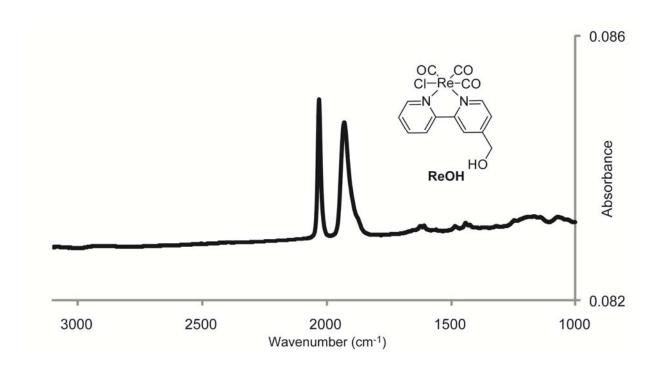
p(Ti, TiO₂) = $2.6*10^{22}$ atoms/cm³, s(N 1s) = 0.477, s(Cl 2p) = 0.891, and s(Re 4f) = 3.961, the surface coverage of bipyridine and rhenium-bipyridine complex on TiO₂ was calculated. For the calculation of surface coverage of organic layers on SiO₂, ρ (Si, SiO₂) = 5.0×10^{22} atoms/cm³ and s(Si 2s) = 0.399 were used.

Synthesis of ReOH

ReOH was synthesized using the literature procedure.⁴ To a 50-mL round bottom flask, **BipyOH** (0.24 g, 1.3 mmol), Re(CO)₅Cl (0.47 g, 1.3 mmol), and methanol (20 mL) were added. The reaction mixture was heated at 60 °C overnight. After cooling down to room temperature, the mixture was precipitated in hexane and then filtered and washed with cold hexane and cold methanol to yield the **ReOH** (0.48 g, 75%). ¹H NMR (300 MHz, DMSO-d₆, δ in ppm): 8.99 (d, J=5 Hz, 2H), 8.93 (d, J=9 Hz, 1H), 8.70 (d, J=8 Hz, 1H), 8.61 (s, 1H), 8.31 (dt, J=1, 8 Hz, 1H), 7.74 (dt, J=1, 8 Hz, 1H), 7.69 (d, J= 6 Hz, 1H), 5.81 (t, J=6 Hz, 1H, -OH), 4.74 (d, J=6 Hz, 2H, -CH₂-). ¹³C NMR (75 MHz, DMSO-d₆, δ in ppm): 197.8, 190.1, 156.8, 155.2, 154.7, 152.9, 152.6, 140.3, 127.8, 124.8, 124.1, 121.2, 61.4.



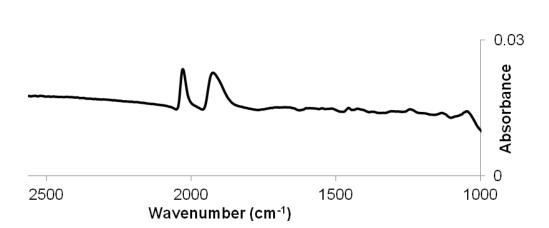
IRRAS spectrum of spin-cast film of ReOH on SiO₂



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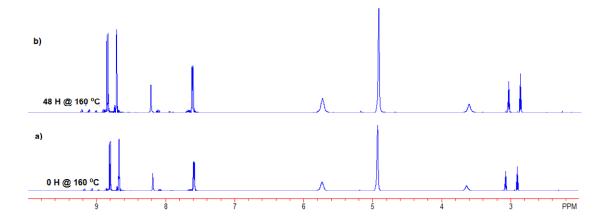
IRRAS spectrum of the grafted layer of rhenium-bipyridine complex (BipyOH-Re) on TiO₂

The IRRAS spectrum of grafted rhenium-bipyridine complex (**BipyOH-Re**) on TiO_2 is similar to that on SiO_2 . Three C=O stretching bands, one at 2024 cm⁻¹ corresponding to the symmetric stretching mode of metal carbonyl groups and two overlapping asymmetric stretching bands at 1905 cm⁻¹ were observed indicating the presence of rhenium-bipyridine complex on TiO_2 surface.



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NMR spectra of Bipy(OH)₂: before and after heating at 160°C for 48 h showing no change in the spectrum. This rules out self-condensation or degradation upon thermal annealing on the substrate to form multilayers. Hence, the higher surface coverage of Bipy(OH)₂ is primararly due to bidentate anchoring to the substrate via ether bond formation.



Reference:

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